



Sheet 1 of 1

Form PTO-1449
(Rev. 2-88)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
5853-224APPLICATION NO.
10/082,010

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

APPLICANT
SINGH, et al.FILING DATE
2/22/02

GROUP

U.S. PATENT DOCUMENTS

EXAMINER'S INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
L.T.M.E.	5,985,748	11/16/99	Watts, et al.	438	622	
L.T.M.E.	6,063,306	5/16/00	Kaufman, et al.	252	79.4	
L.T.M.E.	5,954,997	9/21/99	Kaufman, et al.	252	79.1	
L.T.M.E.	6,126,853	10/3/00	Kaufman, et al.	252	79.1	
L.T.M.E.	6,046,112	4/4/00	Wang	438	693	

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Stöber, W., et al. "Controlled Growth of Monodisperse Silica Spheres in the Micron Size Range", <i>Journal of Colloid and Interface Science</i> , Vol. 26 (1968), pgs. 62-69; and
L.T.M.E.		Rosen, M.J., "Surfactants and Interfacial Phenomena" John Wiley & Sons, 1989, pgs. 3-32, 52-54, 70-80, 122-132 and 398-401.
L.T.M.E.		

EXAMINER	Lynette J. May - Emini	DATE CONSIDERED	11/13/2003
* EXAMINER: Initial if a citation is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			

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U.S. PATENT DOCUMENTS

EXAMINER'S INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
L.T.M.-E	5,954,997	09/21/1999	Kaufman et al.	252	79.1	
L.T.M.-E	6,454,819 B1	09/24/2002	Yano et al.	51	298	

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	Country	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

L.T.M.-E		Luo et al., "CHEMICAL-MECHANICAL POLISHING OF COPPER IN ACIDIC MEDIA," CMP-MIC Conference, 145-151, 1996

EXAMINER

Lynette J. Umeg-Eronini

DATE CONSIDERED

11/5/2003

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